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(71) 申请人: 上海微电子装备 (集团) 股份有限公司
(SHANGHAI MICRO ELECTRONICS EQUIPMENT
(GROUP) CO., LTD.) [CN/CN]; 中国上海市浦东新区张江高科技园区张东路 1525 号 201203 (CN)。

(72) 发明人: 陈志刚 (CHEN, Zhigang); 中国上海市浦东新区张江高科技园区张东路 1525 号 201203 (CN)。张凯 (ZHANG, Kai); 中国上海市浦东新区张江高科技园区张东路 1525 号 201203 (CN)。刘鑫 (LIU, Xin); 中国上海市浦东新区张江高科技园区张东路 1525 号 201203 (CN)。孔伟

(KONG, Wei); 中国上海市浦东新区张江高科技园区张东路 1525 号 201203 (CN)。周许超 (ZHOU, Xuchao); 中国上海市浦东新区张江高科技园区张东路 1525 号 201203 (CN)。

(74) 代理人: 上海思捷知识产权代理有限公司
(SHANGHAI SAVVY IP AGENCY CO., LTD.); 中国上海市黄浦区复兴中路 1 号申能国际大厦 607 室 200021 (CN)。

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(54) Title: OPTICAL DETECTION METHOD

(54) 发明名称: 光学检测方法

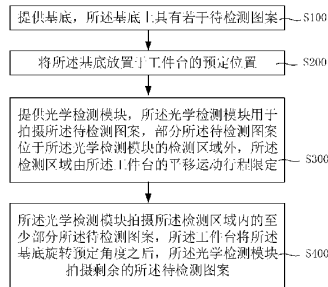


图 1

S100 Provide a substrate, which is provided with several patterns to be subjected to detection
S200 Place the substrate at a predetermined position of a workpiece table
S300 Provide an optical detection module, which is used for photographing the patterns to be subjected to detection, wherein some of the patterns to be subjected to detection are located outside a detection area of the optical detection module, and the detection area is limited by means of a translation motion stroke of the workpiece table
S400 The optical detection module photographs at least some of the patterns to be subjected to detection that are within the detection area, and after the workpiece table rotates the substrate by a predetermined angle, the optical detection module photographs the remaining patterns to be subjected to detection

(57) Abstract: An optical detection method. A substrate (100) is placed at a predetermined position of a workpiece table (200); first, an optical detection module (300) is made to photograph, one by one, at least some patterns to be subjected to detection (101) which are within a detection area (102) of the optical detection module (300); then, the workpiece table (200) rotates the substrate (100) by a predetermined angle, such that patterns to be subjected to detection (101) which are outside the detection area (102) enter the detection area (102); and in this case, the optical detection module (300) photographs, one by one, the remaining patterns to be subjected to detection (101). Therefore, there is no requirement to increase a translation motion stroke of the workpiece table (200) and the motion precision at a distal stroke position, and there is also no requirement to adjust the frame structure and overall layout of a whole machine, thereby reducing the cost and occupied area of the whole machine, and improving the process adaptability.

(57) 摘要: 一种光学检测方法, 将基底 (100) 放置于工件台 (200) 的预定位置, 先令光学检测模块 (300) 逐一拍摄光学检测模块 (300) 的检测区域 (102) 内的至少部分待检测图案 (101), 然后工件台 (200) 将基底 (100) 旋转预定角度, 使得检测区域 (102) 之外的待检测图案 (101) 进入检测区域 (102) 内, 此时, 光学检测模块 (300) 逐一拍摄剩余的待检测图案 (101), 从而无需增加工件台 (200) 的平移运动行程以及远行程位置处的运动精度, 也不用调整整机框架结构及整体布局, 降低了整机的成本及占地面积, 提升工艺适应性。

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